

GP 2851
#15/D
5-17-00
Robertson

XA-7889A Re

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

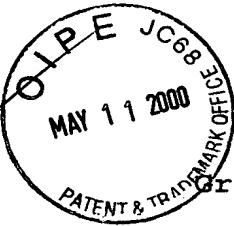
In re the Application of:

Kenji NISHI

Appln. No.: 08/994,758

Filed: December 19, 1997

For: PROJECTION EXPOSURE APPARATUS



Group Art Unit: 2851

Examiner: A. Mathews

AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office communication dated April 11, 2000, please amend the above-identified patent application as indicated below.

IN THE CLAIMS:

Please add the following new claims:

1 --169. An exposure apparatus in which a portion of a
2 pattern of an original is projected onto a substrate and in
3 which the original and the substrate are scanned
4 synchronously such that the pattern of the original is
5 transferred to the substrate, said apparatus comprising:

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